

AMENDMENTS TO THE CLAIMS

1. – 7. (cancelled).

8. (cancelled).

9. – 11. (cancelled).

12. (previously presented) A method for producing a fluorescent material containing PMMA and a fluorescent substance, which comprises a step of dissolving in a solvent PMMA and a fluorescent substance having a xanthene skeleton and a lactone ring and/or a fluorescent substance having a xanthene skeleton and a group -COOR, where R represents a hydrogen atom or a substituent, capable of forming an intramolecular lactone ring to form a solution, wherein the amount of the PMMA is from 5 to 35 % by weight of the solvent, and a step of removing the solvent from the solution.

13. (previously presented) A method for producing a film containing PMMA and a fluorescent substance, which comprises a step of dissolving in a solvent PMMA and a fluorescent substance having a xanthene skeleton and a lactone ring and/or a fluorescent substance having a xanthene skeleton and a group -COOR, where R represents a hydrogen atom or a substituent, capable of forming an intramolecular lactone ring to form a solution, wherein the amount of the PMMA is from 5 to 35 % by weight of the solvent, and a step of removing the solvent from the solution.

14. (original) The method for film production as claimed in claim 13, wherein the solvent is a non-polar solvent.

15. (original) The method for film production as claimed in claim 13, wherein the solvent is a cellosolve acetate.

16. (cancelled).

17. (original) The method for film production as claimed in claim 13, which includes a step of forming the film in a mode of spin coating.

18. (original) The method for film production as claimed in claim 13, which includes a step of forming the film having a thickness of at most 10 μm in a mode of spin coating.

19. (original) The method for film production as claimed in claim 13, which includes a step of forming the film having a thickness of from 1 to 10 μm in a mode of spin coating.

20. (original) The method for film production as claimed in claim 13, which includes a step of forming the film having a thickness of at most 1 μm in a mode of spin coating.